



[10020005-1]

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Jean-Luc Truche et al.
Serial No. : 10/080,879
Filed : February 22, 2002
Title : APPARATUS AND METHOD FOR ION
PRODUCTION ENHANCEMENT

6/A
4-10-03

Art Unit : 2881

Examiner : Bernard E. Sou

Assistant Commissioner
for Patents
Washington, D.C. 20231

Whereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope
addressed to: Assistant Commissioner for Patents, Washington,
D.C. 20231, on

Date 3/10/2003 Atty's Reg. # 33,865

Atty's Signature AARON B. DEDITCH

AMENDMENT

Sir:

In response to the Office Action mailed on October 24, 2002(the three-month response date for which has been extended by two months from January 24, 2003 to March 24, 2003 by the accompanying Transmittal and Petition To Extend), please reconsider the above identified application based on the following:

IN THE ABSTRACT:

Please replace/amend the Abstract as follows:

An apparatus and method for use with a mass spectrometer, in which an ion enhancement system directs a heated gas to heat ions produced by a matrix based ion source and detected by a detector of the mass spectrometer. The ion enhancement system is interposed between the ion source and the detector of the mass spectrometer. The analyte ions that contact the heated gas are enhanced to increase the number and/or intensity of ions detected by the detector of the mass spectrometer. The method includes producing analyte ions from a matrix based ion source, enhancing the analyte ions with an ion enhancement system and detecting the analyte ions with the detector of the mass spectrometer.

IN THE DRAWINGS:

Figure 7 has been corrected to eliminate the text "Prior Art". The correction is in red ink. Approval is respectfully requested.

IN THE SPECIFICATION:

Please amend without prejudice the Specification as follows:

BEST AVAILABLE COPY